

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :  
" :  
**Shinichi IMAI, et al.** :  
: :  
Serial No.: : Group Art Unit:  
: :  
Filed: July 14, 2003 : Examiner:  
: :  
For: SYSTEM AND METHOD FOR MONITORING SEMICONDUCTOR PRODUCTION  
APPARATUS

**CLAIM OF PRIORITY**

Mail Stop CPD  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 35 U.S.C. 119, Applicants hereby claim the priority of:

**Japanese Patent Application No. 2002-205667, filed July 15, 2002**

cited in the Declaration of the present application. A certified copy will be filed in due course.

Respectfully submitted,

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